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Notice of Allowability	Application No.	Applicant(s)	
	10/769,549	WEEKS ET AL.	
	Examiner Rakesh K. Dhingra	Art Unit 1763	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address--

All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.

1. This communication is responsive to applicant's remarks dt 6/26/06 in response to non-final office action.
2. The allowed claim(s) is/are 1,10-21,24-26,28-31 and 38-40.
3. Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
 - a) All
 - b) Some*
 - c) None
 of the:
 1. Certified copies of the priority documents have been received.
 2. Certified copies of the priority documents have been received in Application No. _____.
 3. Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).

* Certified copies not received: _____.

Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application.
THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.

4. A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.
5. CORRECTED DRAWINGS (as "replacement sheets") must be submitted.
 - (a) including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached
 - 1) hereto or 2) to Paper No./Mail Date _____.
 - (b) including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date _____.

Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).
6. DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.

Attachment(s)

1. Notice of References Cited (PTO-892)
2. Notice of Draftsperson's Patent Drawing Review (PTO-948)
3. Information Disclosure Statements (PTO/SB/08),
Paper No./Mail Date _____
4. Examiner's Comment Regarding Requirement for Deposit
of Biological Material
5. Notice of Informal Patent Application
6. Interview Summary (PTO-413),
Paper No./Mail Date _____.
7. Examiner's Amendment/Comment
8. Examiner's Statement of Reasons for Allowance
9. Other _____.



Rakesh K. Dhingra

EXAMINER'S AMENDMENT

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Sanjivpal S. Gill on 9/12/06.

The application has been amended as follows:

In the Claims

Claims have been amended as follows:

1. (Currently Amended) A support assembly for supporting a substrate holder during semiconductor substrate processing, comprising-
a substrate holder support configured to support a substrate holder and to be supported by a rotational drive for rotating the substrate holder support; and
a rotational drive for rotating the substrate holder support;
a retaining member configured to couple the substrate holder support to the rotational drive to thereby prevent rotational slippage of the substrate holder support relative to the rotational drive, the retaining member being selectively removable from the substrate holder support and the rotational drive[.]; and
a securing element that enables selective engagement/disengagement of the retaining member between the substrate holder support and the rotational drive.

10. (Currently Amended) The support assembly of Claim 1, wherein ~~further comprising the rotational drive, the rotational drive compris[ing]es~~ is an elongated shaft

having a longitudinal axis and an outer surface, the shaft having at least one indentation in the outer surface, the indentation being configured to be engaged by the retaining member.

18. (Currently Amended) The support assembly of Claim 1, wherein ~~further comprising the rotational drive,~~ the rotational drive compris[ing]es a shaft having at least one indentation, and the substrate holder support comprising a socket configured to receive a portion of the shaft, the support having an opening located in a sidewall of the socket, the support being configured so that insertion of the retaining member into the opening engages the retaining member with the at least one indentation in the shaft to prevent rotation of the substrate holder support with respect to the shaft.

21. (Currently Amended) The support assembly of Claim 20, ~~further comprising a lock for~~ wherein the securing element enables selectively securing the retaining member in the slot.

39. (Currently Amended) A semiconductor substrate processing system, comprising:
a support member having a receptor and a plurality of arms extending generally radially outward from the receptor, the arms being configured to support an underside of a substrate holder, the receptor having a ~~an~~ hole in a sidewall of the receptor;
a locking key; and
an elongated [[a]] rotational linkage having an end portion configured to be received within the receptor such that the rotational linkage is at least partially rotatable with respect to the receptor about a longitudinal axis of the rotational linkage, the end portion having at least one retaining surface, the at least one retaining surface and the hole configured so that when the rotational linkage is rotated to a locking position, the at

least one retaining surface and the hole together form a passage sized and configured to receive the locking key in a manner such that the locking key prevents the support member from rotating independently of the rotational linkage[.];
a securing element that enables selective engagement/disengagement of the locking key between the support member and the rotational linkage.

In the Specification

Paragraph 42 is amended as follows:

In line 14 – replace “ the shaft 20 wafer holder 22” with “the shaft 20 from wafer holder 16”.

Allowable Subject Matter

The following is an examiner's statement of reasons for allowance:

Claim 1: Prior art (US PGPUB No. 2003/0224105, Chondroudis et al) does not teach claim limitation interalia, “a securing element that enables selective engagement/disengagement of the retaining member between the substrate holder support and the rotational drive”.

Claims 1, 10-21, 24-26, 28-31, 38-40 allowed.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled “Comments on Statement of Reasons for Allowance.”

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Rakesh K. Dhingra whose telephone number is (571)-272-5959. The examiner can normally be reached on 8:30 -6:00 (Monday - Friday).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Parviz Hassanzadeh can be reached on (571)-272-1435. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.


Rakesh Dhingra


Parviz Hassanzadeh
Supervisory Patent Examiner
Art Unit 1763